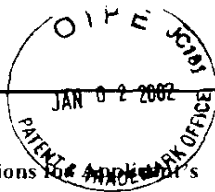


Form PTO-1449 (modified)

List of Patents and Publications

## INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Atty. Docket No.  
2000.082800/TT4490Serial No.  
09/911,264Applicant  
Richard J. Markle and Robert J. ChongFiling Date:  
July 23, 2001Group:  
1762U.S. Patent Documents  
See Page 1Foreign Patent Documents  
See Page 1Other Art  
See Page 1

## U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
	A1						
	A2						
	A3						
	A4						
	A5						

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## Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1						
	B2						
	B3						

## Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
LV	C1	Christel <i>et al.</i> , "Single-Crystal Silicon Pressure Sensors with 500 x Overpressure Protection," <i>Sensors and Actuators</i> , A21-A23:84-88, 1990
	C2	Guckel, "Surface Micromachined Pressure Transducers," <i>Sensors and Actuators</i> , A28:133-46, 1991
	C3	Ko <i>et al.</i> , "A High Sensitivity Integrated-Circuit Capacitive Pressure Transducer," <i>IEEE Transactions on Electron Devices</i> , ED-29:48-56, 1982
	C4	Lee and Wise, "A Batch-Fabricated Silicon Capacitive Pressure Transducer with Low Temperature Sensitivity," <i>IEEE Transactions on Electron Devices</i> , ED-29:42-48, 1982
	C5	Mailon <i>et al.</i> , "Low-Pressure Sensors Employing Bossed Diaphragms and Precision Etch-Stopping," <i>Sensors and Actuators</i> , A21-A23:89-95, 1990
LV	C6	Sander <i>et al.</i> , "A Monolithic Capacitive Pressure Sensor with Pulse-Period Output," <i>IEEE Transactions on Electron Devices</i> , ED-27:927-30, 1980

EXAMINER: LAN VINLI

DATE CONSIDERED: 11/25/2003

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